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JFW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **NAKATA, Yoshihiro et al.**

Group Art Unit: 1771

Serial No.: 10/807,174

Examiner: Hai VO

Filed: March 24, 2004

P.T.O. Confirmation No.: 4205

**FOR: SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,  
SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW  
DIELECTRIC CONSTANT FILM**

**RESPONSE UNDER 37 CFR §1.116**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

June 30, 2006

Sir:

In response to the Office Action dated March 31, 2006, please amend the above-identified application as follows:

C.K.  
to Enter  
9/13/06  
AEJ

Do not enter,

HV

~~07/09/06~~